



Traceability Japan TC Chapter Meeting Summary and Minutes

SEMICON Japan 2015

Friday, December 18, 2015

Tokyo Big Sight Conference Tower, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs: Hirokazu Tsunobuchi (KEYENCE), Yoichi Iga

SEMI Staff: James Amano

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
KEYENCE	Tsunobuchi	Hirokazu	Consultant	Yoshise	Masanori
Consultants	Iga	Yoichi	Consultant	Kumai	Sadao
SUMCO	Nakai	Tetsuya	HST Vision	Sasaki	Kumihiko

Table 2 Leadership Changes

None

Table 3 Ballot Results (or move to Section 4, Ballot Review)

Passed ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

Failed ballots and line items were returned to the originating task forces for re-work and re-balloting.

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
5890	Revision to SEMI T7-0415 Specification for back surface marking of double-side polished wafers with a two-dimensional matrix code symbol	Passed with editorial changes

Table 4 Authorized Ballots

<i>#</i>	<i>When</i>	<i>SC/TF/WG</i>	<i>Details</i>
5971	2016	Five-year Review TF	Reapproval ballot for: SEMI T19-0311: Specification for Device Marking (to be intercommittee balloted to Silicon Wafer Committee)

Table 5 Authorized Activities

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
5971	SNARF	Five-year Review TF	Reapproval ballot for: SEMI T19-0311: Specification for Device Marking

NOTE 1: SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

Table 6 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
20151218#1	James Amano	James Amano to make sure that M12 and M13 reapproval or revision ballots are intercommittee balloted to the Silicon Wafer Committee.

Table 7 Previous Meeting Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
20141205#1	Fiducial Mark Interoperability TF	To revise the SNARF for Line Item Revision to Doc. 5752: Revision of SEMI T7-0303 (Reapproved 0709), Specification for Back Surface Marking of Double-Side Polished Wafers with a Two-Dimensional Matrix Code Symbol CLOSED

1 Welcome, Reminders, and Introductions

Co-chair Hirokazu Tsunobuchi called the meeting to order at 10:15. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01_Required_Elements_Reg_20150327_J

2 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting.

Motion: To approve the minutes as submitted.

By / 2nd: Masanori Yoshise/Tetsuya Nakai

Discussion: None

Vote: 4-0, Motion passed.

3 Liaison Reports

3.1 NA Traceability Committee Chapter

James Amano reported. Of note:

- Five-year review: To be discussed in NA Standards Spring Meeting 2016
 - SEMI M13-0706 (Reapproved 1011)
 - Specification for Alphanumeric Marking of Silicon Wafers
 - SEMI M12-0706 (Reapproved 1011)
 - Specification for Serial Alphanumeric Marking of the Front Surface of Wafers
 - Discussion: Iga-san asked if it would be preferable for these documents to be transferred to the Silicon Wafer Committee. His reasoning was that the expertise might not be available in the Traceability Committee. James responded that the Reapproval ballots would be intercommittee balloted to the Silicon Wafer Committee

Action Item: James Amano to make sure that M12 and M13 ballots are intercommittee balloted to the Silicon Wafer Committee.

Attachment: 02_NA Trace Liaison Report Fall 2015 LNN rev1

3.2 SEMI Staff Report

James Amano (SEMI) gave the SEMI Staff Report. The report included info on:

- SEMI Global 2015 & 2016 Calendar of Events,
- Global Standards Meeting Schedule, 2016 Critical Dates for SEMI Standards Ballots,
- SEMI Standards Publications,

- Info on SEMICON Japan 2016
- SEMI Standards Awards
- **Note:** Ballot critical dates for 2016 are now online at: http://www.semi.org/en/Standards/P_000788

Attachment: 03_SEMI Staff Report 20151215_r1

4 Ballot Review

4.1 Document#5890: Revision to SEMI T7-0415 Specification for back surface marking of double-side polished wafers with a two-dimensional matrix code symbol

- 5890 was approved by the committee with editorial changes. Details can be found in the below attachment.

Attachment: 04_5890_Procedural Review

5 Subcommittee & Task Force Reports

5.1 Fiducial Mark Interoperability Task Force

Ballot 5890 was adjudicated (and approved) at today's meeting.

Attachment: 05_20151118FMI-TF_r0.2

6 Old Business

6.1 *Five-year Review*

- SEMI T12-0710: Specification for Tracing Jigs and Implements
- SEMI T13-1104 (Reapproved 0710): Specification for Device Tracking: Concepts, Behavior, and Services

Motion: To allow T12 and T13 to go inactive.

By / 2nd: Tetsuya Nakai/Masanori Yoshise

Discussion: None

Vote: 5-0

- SEMI T19-0311: Specification for Device Marking
 - Members agreed that T19 is still used by the industry, and that it should be sent out for Reapproval. (See "New Business" below)

6.2 PV Traceability TF

This TF has had no activity for over two years.

Motion: To disband the PV Traceability TF.

By / 2nd: Tetsuya Nakai/Masanori Yoshise

Discussion: None

Vote: 5-0

7 New Business

7.1 *New SNARFs*

- Reapproval ballot for: SEMI T19-0311: Specification for Device Marking

Motion: To approve the above SNARF



By / 2nd: Tetsuya Nakai/Masanori Yoshise
Discussion: None
Vote: 5-0
Motion: To issue the Reapproval ballot for T19 in 2016
By / 2nd: Tetsuya Nakai/Masanori Yoshise
Discussion: None
Vote: 5-0

8 Action Item Review

8.1 Open Action Items

James Amano (SEMI) reviewed the open action items. These can be found in the Open Action Items table at the beginning of these minutes.

8.2 New Action Items

James Amano (SEMI) reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

9 Next Meeting and Adjournment

The next meeting of the Japan Traceability Committee Chapter, when determined, will be posted to the Standards Calendar on the SEMI Web site.

Respectfully submitted by:

James Amano/SEMI HQ

Minutes approved by:

Yoichi Iga (JSA), Co-chair	February 19, 2016
Hirokazu Tsunobuchi (Keyence), Co-chair	February 19, 2016

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org.